

ECLIPSE MA200 MA100N

Inverted Metallurgical Microscopes



MA200/MA100N

Features



	Brightfield	Darkfield	Simple polarizing	DIC	Fluorescence
Compatible observation	0	0	0	0	\triangle
methods	*DIA illuminator i	is available for tra	ansmitted light ob	servation.	

 \triangle : only available with Halogen Lamp and Fiber Illumination

- LV-LH50PC 12V50W Halogen Lamp Illuminator
 - C-HGFI HG Precentered Fiber Illuminator (option) LV-LL LED Lamphouse

Magnification module

Compatible

illminators

Compatible stages

• MA2-SR Mechanical Stage (stroke: 50 x 50 mm)

• 1x/1.5x/2x

Simple polarizing Brightfield Darkfield DIC **Fluorescence**

MA100N

Designated for brightfield and simple polarizing observation, the MA100 is a

cost-effective solution to manufacturing and QA/QC situations in industries

such as automotive/electronic parts and industrial machinery/tools.

*Dedicated reflected illumination models

High-intensity white LED Illuminator (internal power supply)

- MA-SR-N Rectangular 3-plate Stage N (stroke: 50 x 50 mm)
- MA-SP-N Plain Stage N
- TS2-S- SM Mechanical Stage (stroke: 126 x 78 mm)

*Please use in combination with MA-SP-N Plain stage N.

ECLIPSE **MA200**



An ideal inverted microscope offered only by Nikon



Front Operation

Delivers ease-of-use by placing all important controls at the front of MA200N.



- Optical path changeover lever (vertical tube/binocular tube)
- Aperture diaphragm dial Field diaphragm dial Brightness control dial
- Operation port for the polarizer/analyzer unit and the fluorescent unit
 - BD field changeover lever Scale slider slot Flexible handle stage

Quick Status Check

Automatically detects the address of the objective lens currently in use and displays it on the main unit front panel.

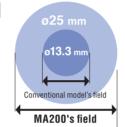
The observation position of the objective lens and sample can be checked easily from the microscope's front panel.

Evolved Optical Performance

Provides a more ergonomic observation with clearer images.

Super-wide field of view

A sample with a diameter of just 25 mm can be observed in an one field of view by combining the ultra wide field of view eyepiece and 1x objective lens.





• T Plan EPI 1x Semi-Apochromat Wide field of view

Even Illumination

Improved uniformity of illumination delivers clear images, especially for digital imaging.

Combine images with the stitching feature

Can combine up to eight images with uniform lighting and no seams.



Box Structure

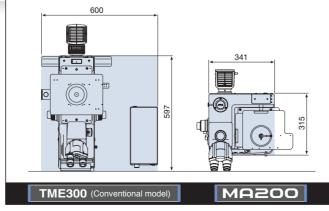
The unique box structure is 1/3 smaller than conventional models and offers improved durability.

Compact structure with a depth of 315 mm

A box shaped microscope, not only the width but also the depth is reduced dramatically: The foot print is only onethird of the conventional model!

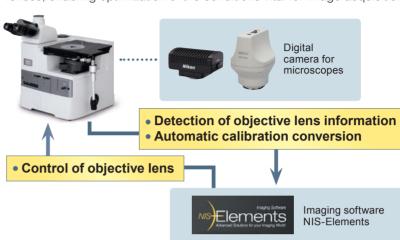
High stability and durability

Reduced vibration during high-power observation, offering a highly rigid microscope.



Combination with Digital Camera

The MA200 allows detection of information and control of objective lenses, enabling optimization of the conditions vital for image acquisition.



Note: With NIS-Flements L and F functions above are not available. Use NIS-Elements D/Br/Ai

Illumination

Expanded lineup

Added a compact LED illuminator to the existing lineup. With the use of LED. Nikon illuminators are power saving and achieve long life.



LV-LL LED Lamphouse

Accessories

Stage

Samples can be rotated by the stage clip. The stage delivers high durability needed to support heavy samples.

1 MA-2 SR Stage





DIC Units

Standard and high contrast type DIC prism are available to match needs of the sample.

These prisms are effective for observation of minute step heights

MA2-PA Unit 2 L-DIHC DIC Prism (High Contrast) 3 L-DIC DIC Prism

Nosepiece & Magnification Module

Enables communication of objective lens position, magnification and intermediate magnification module information with the NIS-Elements image software.

1 MA2-MC

Magnification Module 2 LV-NU5I Intelligent Universal Quintuple



Holders

A full lineup is available that correspond to a variety of sample shapes.



Polarizing Units

Polarizing observation is effective for birefringence samples. MA2-PA unit is suitable for observation of aluminium.



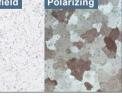
Single-action operation

Links the attachment/release of the analyzer/polarizer.

1 MA2-PA Unit 2 MA2-UPA Unit*

3 MA2-λPλ Plate *It is suitable for inspecting aluminium sample.





Grain Size Reticle & Scale

Overlays a pattern onto the observed image. The Grain Size Reticle is used for grain size analysis and complies with the JIS G0551 and ASTM E112 standards. The Scale displays a scale for each objective lens magnification.

1 MA2-GR Grain Size Reticle JIS G0551/objective lense 10x (100× magnification) ASTM E112/objective lense 10x (100× magnification) MA2-MR Scale



ECLIPSE

MA100N

A durable, user-friendly Inverted Microscope with superior image quality, a small footprint and great cost performance.



Illumination

Employment of high-intensity LED illumination (Eco-illumination)

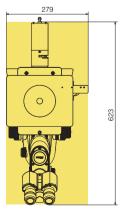
Compared to conventional halogen illumination, these high intensity LED sources need only about one third of consuming electricity and last approximately 30 times longer. The MA100N ensures stable sample observation with uniform color temperature even in different light intensity.



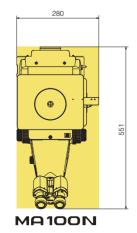
Compact Body

Redesigned to be smaller

Designed for LED illumination, the footprint is 11% smaller than conventional models, allowing users to have more installation choices.



Previous model (MA100L)



Stage

Controlled stability even with heavy samples/ Boasts superior durability

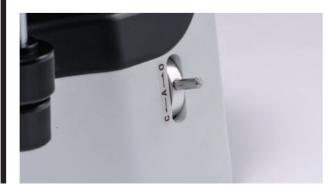
The MA-SR-N Rectangular Stage was developed especially for the MA100N. The three-plate structure allows for observation of heavy samples, such as a grinder resin mounted samples.



Aperture Diaphragm

Standard with MA100N

The epi illuminator comes standard with a variable aperture diaphragm to control image contrast and depth of field.



Accessories



Digital Camera

Redesigned with optical systems suitable for sample observations. The camera port is located on the side of MA100N to provide improved visibility of the stage.

3 TS2-P-CF

Camera port 100

Microscope Camera DS-Fi3 2 C-0.63x-TS2 C-mount Adapter



Basic stage set

A triple-platform stage structure lets you use heavy samples.

- 1 MA-SR-N Rectangular Stage N
- 2 Specimen Holder (ø20/30/40 mm aperture)
- 3 MA-SH3 Specimen Holder 3 4 MA-SRSH1 Universal
- Specimen Holder



Grain size reticle

The class of grain size in a sample can be easily distinguished while observing its image.

MA100-EPRGS Grain Size Reticle



7 MA-SRSH1 Universal

Specimen Holder

Holder 1N

9 MA-P/A Simple

8 MA-SH1-N Specimen

Other accessories

- 1 TI-SM Mechanical Stage CH
- 2 MA-SP-N Plain Stage N MA-SH2-N Specimen Holder 2N
- 4 MA-S-HU Universal Holder
- 5 MA-SH3 Specimen Holder 3
- 6 MA-SRSH 25-40 Holder





Accessories



Nikon's CFI60 optical system, highly evaluated for its unique concept of high NA and long working distance, has achieved the apex in long working distance, chromatic aberration correction, and light weight.

Standard objective lenses

TU Plan Fluor Series

EPI/BD 5x/10x/20x/50x/100x

Enable brightfield, darkfield, simple polarizing, sensitive polarizing, differential

interference, and epi-fluorescence observations with just one lens. Achieves superior chromatic aberration performance with long working distance for all magnifications to adapt to any application.











*Brightfield observation (EPI) objective lens

Model	Magnification	NA	Working Distance (mm)
TU Plan Fluor EPI	5×	0.15	23.5
(brightfield type)	10×	0.30	17.5
	20×	0.45	4.5
	50×	0.80	1.0
	100×	0.90	1.0
TU Plan Fluor BD	5×	0.15	18.0
(brightfield/ darkfield type)	10×	0.30	15.0
	20×	0.45	4.5
	50×	0.80	1.0
	100×	0.90	1.0

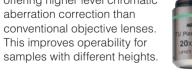
Long working distance objective lenses

TU Plan ELWD Series

EPI/BD 20x/50x/100x



lenses enable long working distances while offering higher level chromatic aberration correction than







*Brightfield observation (EPI) objective lens

Model	Magnification	NA	Working Distance (mm)
TU Plan EPI ELWD	20×	0.4	19.0
(brightfield type)	50×	0.6	11.0
	100×	0.8	4.5
TU Plan BD ELWD	20×	0.4	19.0
(brightfield/ darkfield type)	50×	0.6	11.0
	100×	0.8	4.5

Low-magnification objective lenses

T Plan EPI EPI 1x/2.5x

Both clear observation using a conventional analyzer/polarizer and operability-oriented observation without the need of an analyzer/ polarizer are possible.



Model	Magnification	NA	Working Distance (mm)
T Plan EPI	1×	0.03	3.8
(brightfield type)	2.5×	0.075	6.5

Apochromatic objective lenses

TU Plan Apo Series



By using phase Fresnel lenses, these objective lenses achieve significantly longer operating distances while maintaining the superior chromatic aberration performance of apochromatic lenses.



*Brightfield observation (EPI) objective lens

Model	Magnification	NA	Working Distance (mm)
TU Plan Apo EPI	50×	0.8	2.0
(brightfield type)	100×	0.9	2.0
	150×	0.9	1.5
TU Plan Apo BD	50×	0.8	2.0
(brightfield/ darkfield type)	100×	0.9	2.0
	150×	0.9	1.5

Other Lenses Brightfield objective lense CFI L Plan EPI 40x

A 40x objective lens is best for metal analysis.

NA: 0.65 W.D.: 1.0 mm



Digital camera system for microscopes

DIGITAL SIGHT SERIES

Microscope camera

DS-Fi3

Frame Rate

Max Recordable

Three main features of the previous models, high-resolution, high sensitivity and low noise, and high-speed live display are offered in 1 camera.



DS-Ri2

Capable of expressing images as is, this microscope digital camera offers high resolution, color reproduction, and frame rate



30 fps (1440×1024)

2880×2048







4908×3264



Imaging software NIS-Elements

Using a tablet PC



Simply installing NIS-Elements L on a table PC enables setting and control of DS-Fi3/ DS-Ri2 microscope cameras, live image display, and image acquisition.



A wide variety of tools

NIS-Elements L enables the conducting of simple measurements on images, with input of lines and comments. These can also be written onto and saved with the image, and measurement data can be output.





Scene Mode

Ten camera setting patterns for optimal color reproduction and contrast for each microscope light source, observation method and type of sample, as well as custom settings, can be selected.

- Wafer/IC Circuit board
- Metal, Ceramic/Plastic
- Flat Panel Display

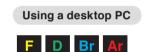
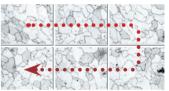




Image Stitching

Stitches together images acquired from multiple fields of view to create one image

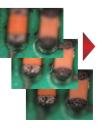






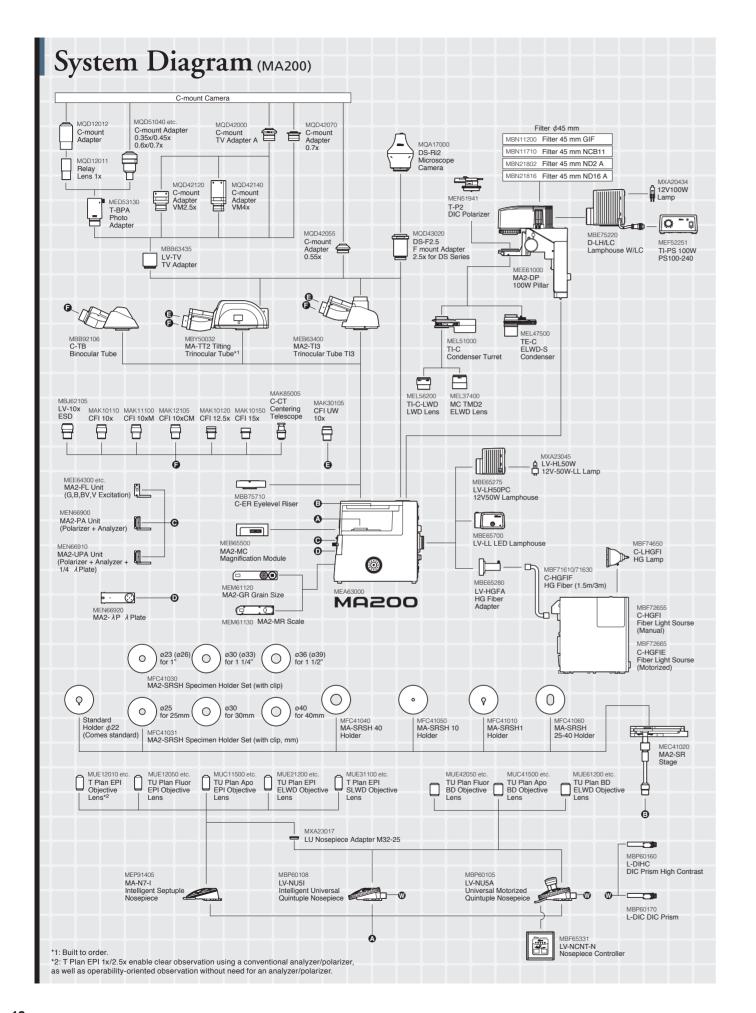
EDF (Extended Depth of Focus)

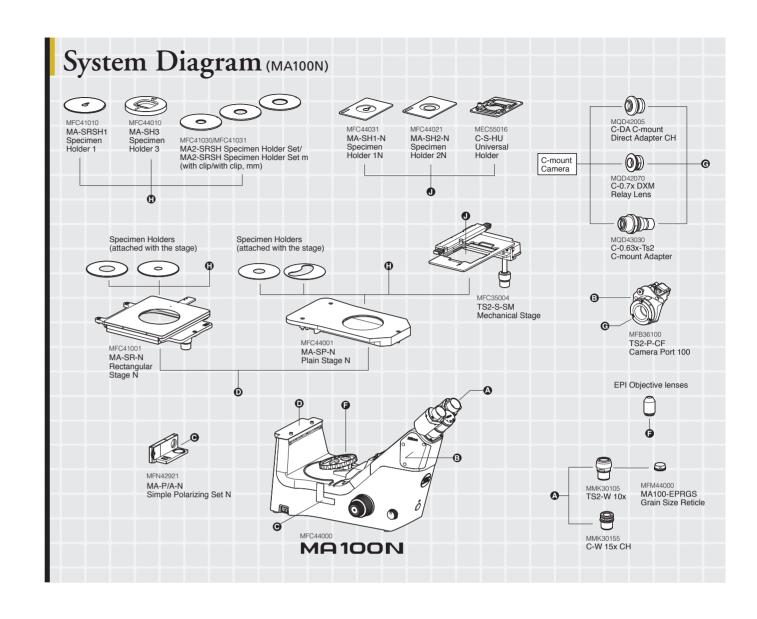
Create a single, all-in-focus image from images of differing



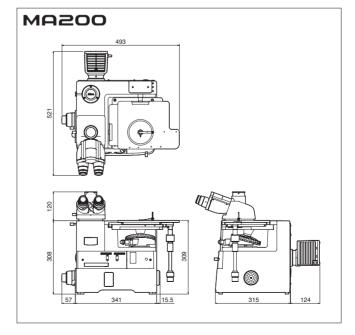


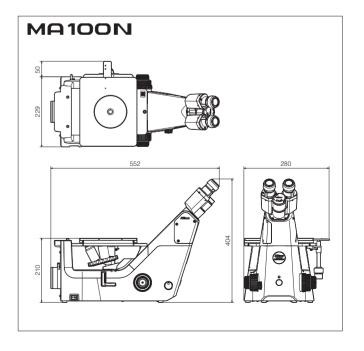
^{*} See the "Digital Camera Digital Sight Series for Microscopes" brochure for details on Digital Sight features.





Dimensions





Specifications (MA200)

_			
		MA200	
Main body	Focusing mechanism Focusing nosepiece (Fixed stage) Coaxial coarse/fine adjustment knob (torque adjustable)		
		Coarse adjustment of 4.0 mm per rotation, fine adjustment of 0.1 mm per rotation	
	Illumination	With flare prevention, Built in UV cut filter	
		Field diaphragm: dialing continuous variable (centerable), Aperture diaphragm: dialing continuous variable (centerable)	
		Filter: Double turret (ND16, ND4/GIF, NCB, Additional option available), Polarizing block (Selectable with or without 1/4 λPlate)	
		Fluorescence filter blocks: B/G/V/BV	
		12V50W Halogen Lamp, C-HGFI HG Fiber Illuminator, LV-LL LED Lamphouse	
	Light distribution	Eyepiece tube/Back port: 100/0, 55/45	
Optics	CFI60/CFI60-2 system		
Observation image	Surface Image		
Observation method	Bright/Darkfield/Simple	Polarizing/DIC/Epi-Fluorescence	
Revolving nosepieces	LV-NU5I: Bright/Darkfie	Id/DIC 5 position nosepiece, LV-NU5A: Motorized Bright/Darkfield/DIC 5 position nosepiece	
	MA-N7-I Brightfield 7 position nosepiece (Intelligent)		
Stage	MA2-SR Mechanical Sta	age (X/Y flexible handle)	
	Dimension: 295×215 mn	n, Stroke: 50 mm×50 mm (with distance graduation), Standard accessory: ø22 universal specimen holder (with sample clip)	
Trinocular eyepiece	Siedentopf interpupillary	y distance adjustment 50-75 mm	
Power source	100-240 V, 50-60 Hz		
Power consumption (max.)	1.2 A 75 W		
Weight	Approx. 26 kg (depends on combination)		
Options	Intermediate magnification	Turret (1x, 1.5x, 2x), Status detection (Output magnification information to main unit)	
	Scale	MA2-GR Grain Reticle (ASTM E112-63 grain sizing numbers 1 to 8), Grid Reticle(20 lines, 0.5 mm)	
		MA2-MR Scale Reticle (compatible with 5-100x, Read in um, Dialing System)	

Specifications (MA100N)

	MA 100N
Optics	CFIeo/CFIeo-2 system
Observation image	Reversed image
Observation method	Brightfield and polarization (with MA P/A simple polarizer/analyzer set)
Focusing	Focusing nosepiece (fixed stage), coaxial coarse/fine adjustment knob with 8.5-mm stroke
	(Coarse adjustment of 37.7 mm per rotation, fine adjustment of 0.2 mm per rotation)
Nosepiece	Brightfield 5-position nosepiece
Stage	MA-SR-N Rectangular 3-plate Stage N: 50×50 mm stroke (includes two stage inserts (@20 mm and 40 mm opening) and coaxial control handle on the right side
	The 3-plate design allows entire top surface to move. Optional Stage inserts: MA-SRSH1 Specimen Holder 1 with (ø15 mm opening or MA-SH3
	Specimen Holder 3 with 2 mm to 32 mm adjustable opening
	MA-SP-N Plain Stage N: 188×310 mm - Includes two stage inserts (1) clear acrylic stage insert with ø30 mm opening, (2) clear acrylic stage insert
	with crescent opening (width 30 mm) to allow clearance for rotation of high magnification objectives
	Optional stage inserts: MA-SRSH1 Specimen Holder 1 with 15 mm opening or MA-SH3 Specimen Holder 3 with 2 mm to 32 mm adjustable opening
	Accepts Attachable Mechanical Stage TI-SM
	TS2-S-SM Mechanical Stage: 126 mm×78 mm stroke, handle can be attached on the right or left side of the plain stage
	Optional Specimen Holders to fit Attachable Mechanical stage: MA-SH1-N Specimen Holder 1N (ø15 mm opening)
	MA-SH2-N Specimen Holder 2N (ø30 mm opening), or C-S-HU Universal Holder (30 mm to 65 mm adjustable opening)
Illuminator	Internal power supply white LED light source, condenser built-in (lever operated), ø25 mm filter can be inserted
Binocular body	Built-in Siedentopf binocular, 45 inclination angle and 50 to 75-mm interpupillary adjustment, attachable camera port, eyepiece/Port: 100/0:0/100
Power consumption (max.)	15W
Weight	Approx. 10 kg

Specifications and equipment are subject to change without any notice or obligation on the part of the manufacturer. April 2019 ©2006-2019 NIKON CORPORATION

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*Products: Hardware and its technical information (including software)



TO ENSURE CORRECT USAGE, READ THE CORRESPONDING MANUALS CAREFULLY BEFORE USING THE EQUIPMENT.



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